



Session Title:	[WE2] Advanced Lithography for Future Optical Devices II
Session Date:	November 22 (Wed.), 2023
Session Time:	10:20-11:50
Session Room:	Room E (Sidney Room, 2F)
Session Chair:	Prof. Hansuek Lee (KAIST, Korea)

[WE2-1] [Invited] 10:20-10:50

Advanced On-Demand Micro-Transfer Printing Techniques for Seamless Integration of Nanophotonic and Metasurface Devices

Moohyuk Kim, Byoung Jun Park, and Myung-Ki Kim (Korea Univ., Korea)

[WE2-2] 10:50-11:10

Double-Layered Disordered Metasurface Spectrometer

Gookho Song, Dong-gu Lee, Chunghyeong Lee, Chanseok Lee, and Mooseok Jang (KAIST, Korea)

[WE2-3] 11:10-11:30

Unconventional Approach for Fabricating Diffractive Optical Elements via Holographic Inscription

Yongjun Lim, Seung Jae Hong, Joon Bang, and Seungwoo Lee (Korea Univ., Korea)

[WE2-4] 11:30-11:50

Self-Assembly-Based Molecular Addressing on Chemically Modified Gold Surface

Sung Hun Park, Chae-Eon Kim, Yongjun Lim, and Seungwoo Lee (Korea Univ., Korea)